PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of		
	Bedell et al.	Group Art Unit: 2652
Application No. 10/602,462		Examiner: CHEN, Tianjie
Filed:	06/23/2003	Attorney Docket No. HIT1P006/HSJ920030045US1
For:	MAGNETIC HEAD COIL SYSTEM) AND DAMASCENE/REACTIVE ION ETCHING METHOD FOR MANUFACTURING THE SAME	Date: May 18, 2007

AMENDMENT WITH RCE 37 C.F.R. §1.114

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Examiner:

Together with the enclosed Request for Continued Examination (RCE, 37 C.F.R. §1.114) and prior to a first action on the merits, kindly amend the claims as indicated below. Applicant also submits the necessary fees.